



AP 1753  
EPL

03500.015382.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: Alan D. Diamond
TAKAHARU KONDO, ET AL.	)	
	:	Group Art Unit: 1753
Application No.: 09/866,665	)	
	:	
Filed: May 30, 2001	)	
	:	
For: SILICON-TYPE THIN FILM	)	
FORMATION PROCESS, SILICON	:	
TYPE THIN FILM, AND	)	
PHOTOVOLTAIC DEVICE	:	April 6, 2005

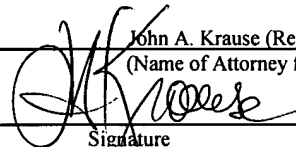
Mail Stop Amendment  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated January 6, 2005, please amend the above-identified application as follows.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on April 6, 2005  
 (Date of Deposit)

John A. Krause (Reg. No. 24,613)  
 (Name of Attorney for Applicants)  
  
 Signature April 6, 2005  
 Date of Signature